



LHC Injectors Upgrade





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Slip stacking in the SPS

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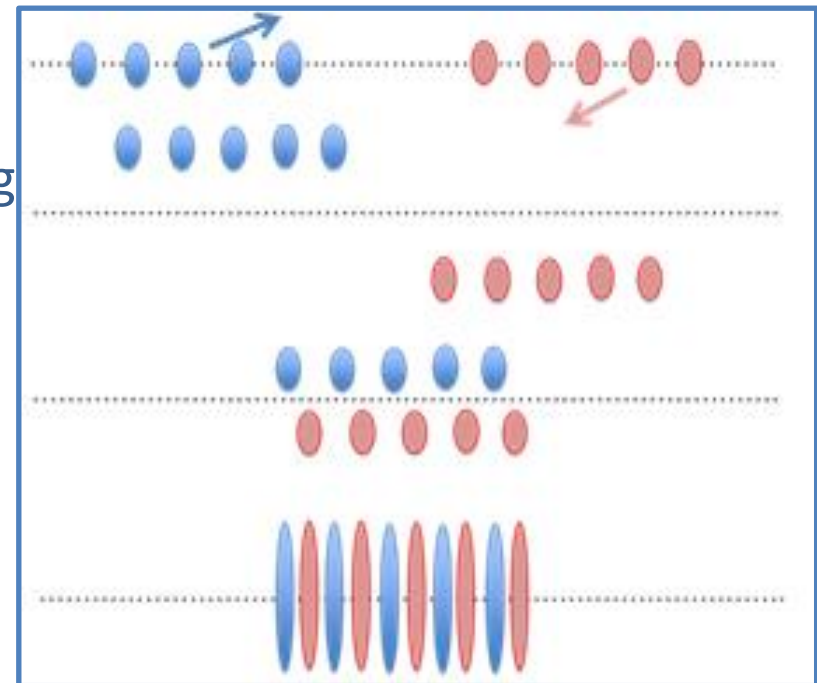
Motivation

- ❑ Increase the peak luminosity for the HL-LHC ($6-7 \times 10^{27} \text{ cm}^{-2} \text{ s}^{-1}$ at 7 ZTeV requested by the ALICE experiment)
(D.Manglunki, RLIUP, Archamps 2013)
- ❑ Increase the number of bunches in the LHC → decrease the bunch spacing (from 100 ns to 50 ns)
- ❑ Bunch-splitting or batch compression difficult to perform in the PS
- ❑ Alternative: momentum slip-stacking in the SPS (R. Garoby)
- ❑ Potential feasibility based on
 - Large bandwidth of the SPS 200 MHz Travelling Wave RF system
 - Relatively small initial emittances
 - Low ion intensity (no need of FB, FF, 800 MHz, ...)



Procedure

- ❑ **Two super-batches injected into the SPS:**
 - **PS batch:** 4 bunches spaced by 100 ns
 - 6 PS batches injected into the SPS (batch space of 100ns)
 - **SPS super-batch:** 24 bunches spaced by 100 ns (2.3 μ s)
- ❑ The two super-batches are captured by the two pairs of 200 MHz TWC \rightarrow **independent beam controls are needed**
- ❑ f_{RF} variation to accelerate the first batch and decelerate the second
- ❑ Let the batches slip
- ❑ Bring them back by decelerating the first and accelerating the second
- ❑ Once the bunches are interleaved they are recaptured at average RF frequency



Basic beam dynamics concept



- The total voltage experienced by both batches

$$V_{tot} = V_0 \sin(\omega_{RF}t - \delta\omega t) + V_0 \sin(\omega_{RF}t + \delta\omega t) \Leftrightarrow \\ V_{tot} = 2V_0 \sin(\omega_{RF}t) \cos(\delta\omega t)$$

V_0 : voltage amplitude of each RF system
 ω_{RF} : RF angular frequency on central orbit
 $\delta\omega$: RF angular frequency offset from ω_{RF}

motion of the bunches is disturbed from the other RF system

- At sufficiently large $\delta\omega$ this excitation averages within a synchrotron oscillation period → **bunches practically independent**
- For constant energy separation and equal RF voltage amplitudes V_0

$$f_{s0} = f_{rev} \sqrt{h|\eta|eV_0/2\pi\beta^2E} \rightarrow \text{small amplitude synchrotron frequency}$$

$$H_B = \sqrt{2\beta^2EeV_0/h|\eta|\pi} \rightarrow \text{Bucket half height}$$

$$\frac{\Delta f_{rev}}{f_{rev}} = -\eta \frac{\Delta E}{\beta^2E}$$

ΔE : Energy difference between the two beams
 Δf_{rev} : difference in revolution frequency between the two beams
 Δf_{RF} : difference in RF frequency between the two beams

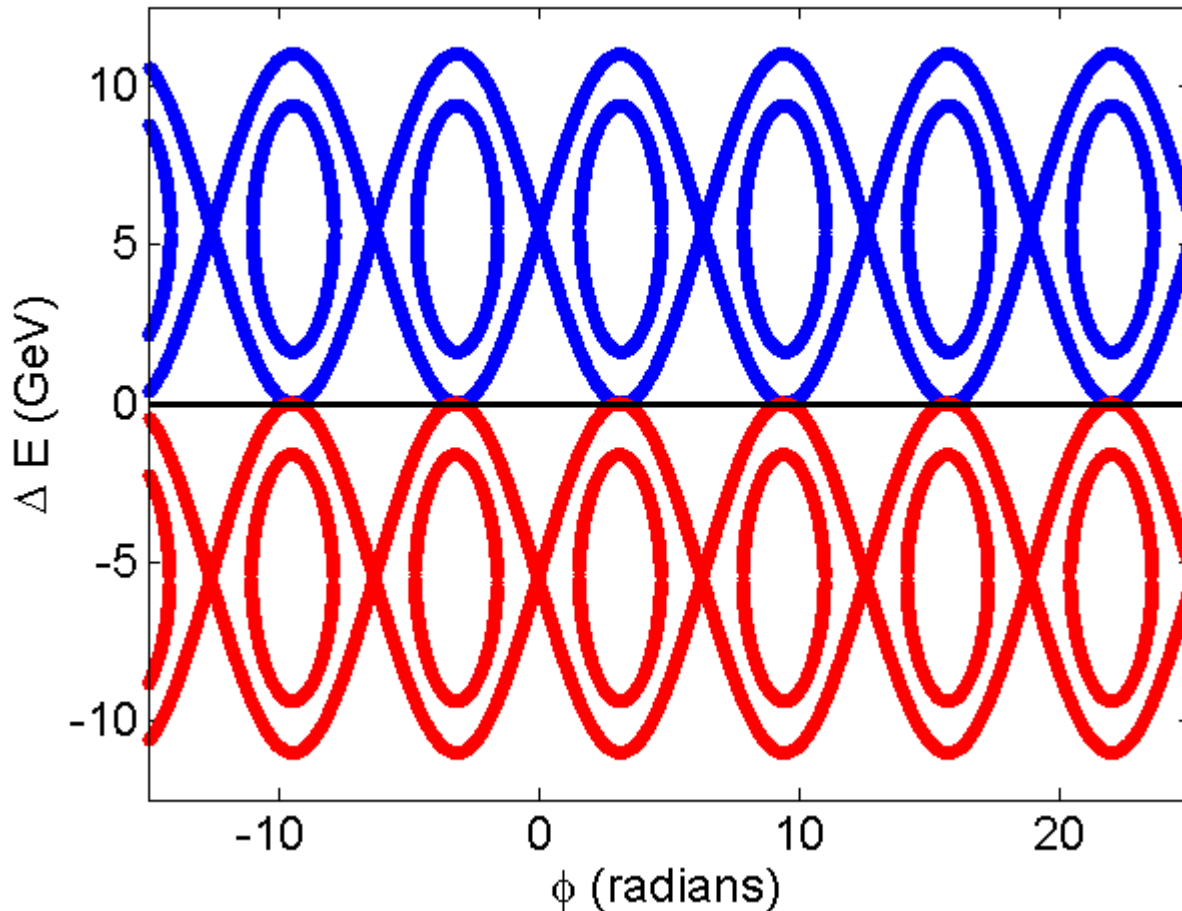
Combining the three equations we get:

$$\alpha \stackrel{\text{def}}{=} \frac{\Delta f_{RF}}{f_{s0}} = 2 \frac{\Delta E}{H_B}$$



Basic beam dynamics concept

turn = 1 - Time = $0.0016T_{s0} = 2e-005$ s



□ $\alpha = 4 \rightarrow \Delta E = 2H_B$:
tangent boundaries for the
two buckets \rightarrow lower limit
for stable motion (F. E.
Mills)

□ **But**, rapid effective
emittance growth from
tracking simulations

□ Acceptable to hold
bunches for several T_s
when $\alpha \geq 8$: space of 1
empty bucket between the
two \rightarrow **large emittance
blow-up when recaptured**

□ Recapture when the 2 RF
Voltages are in phase \rightarrow
**disturbed bunch shape
with empty phase-space in
 $\Delta E = 0$**





Energy consideration

❑ Flat bottom

- Strong effects of space charge, IBS and RF noise (observed during operation)

❑ Flat top

- Extra time for filamentation is needed
- Uncaptured beam will be transferred into the LHC

❑ Intermediate energy plateau

- Benefits due to high energy (no IBS, space charge)
- Filamentation during the ramp to top energy
- Clean beam for the LHC

**Simulations presented below were performed at 300 GeV/c
(proton equivalent)**

Slip stacking at 300 GeV/c (proton equivalent)

- ❑ Longitudinal emittance: $\epsilon_l = 0.125$ eVs/A
- ❑ Initial RF Voltage: $V_{RF} = 0.34$ MV (filling factor in momentum of 0.9)
- ❑ Maximum momentum separation: $dp/p = 1.84 \times 10^{-3}$ → much larger than the bucket height (0.22×10^{-3}) but within the aperture limit → **reduce slip time and minimize the mutual influence of the two beam during the slip**

Initial conditions used in the simulations for slip-stacking

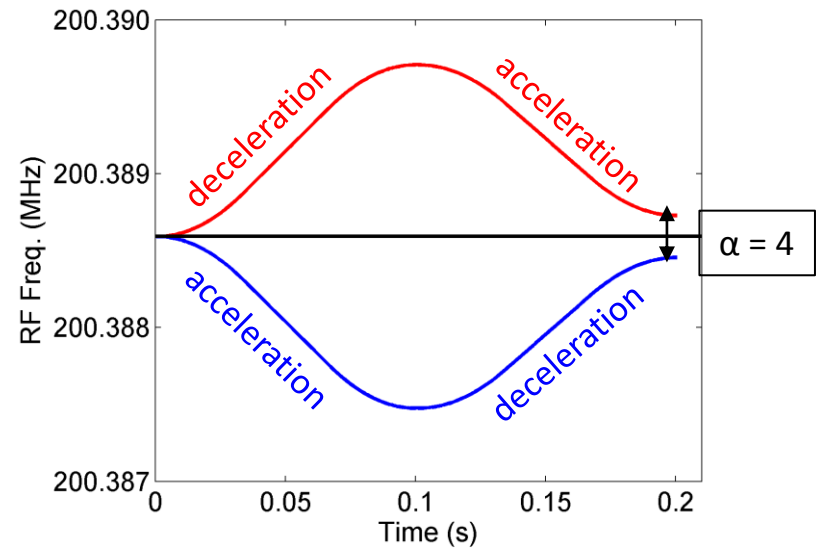
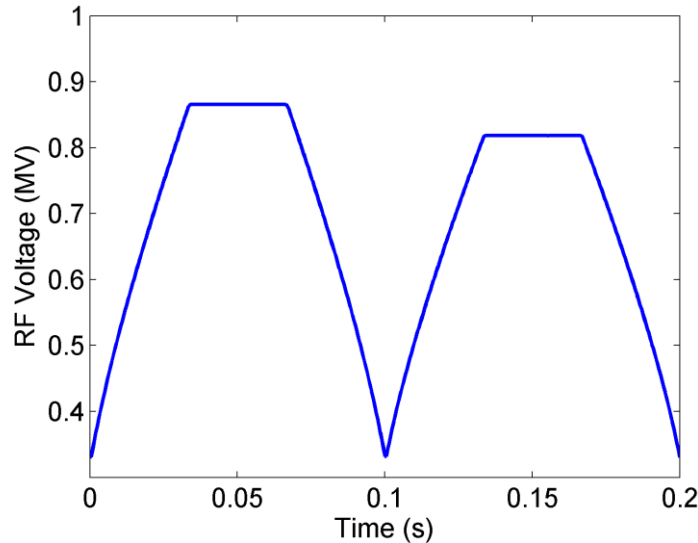
Parameter	Symbol	Value	Units
Lorentz factor	γ	127	-
Slippage factor	η	3×10^{-3}	-
Longitudinal emittance	ϵ_l	0.125	eVs/A
RF voltage amplitude	V_{RF}	0.34	MV
Small amplitude synchrotron frequency	f_{s0}	68	Hz
Maximum momentum separation per beam	dp/p	1.84×10^{-3}	-
Maximum radial displacement per beam	ΔR	6.0	mm
Frequency offset per beam	Δf_{RF}	1116	Hz





Designed RF programs

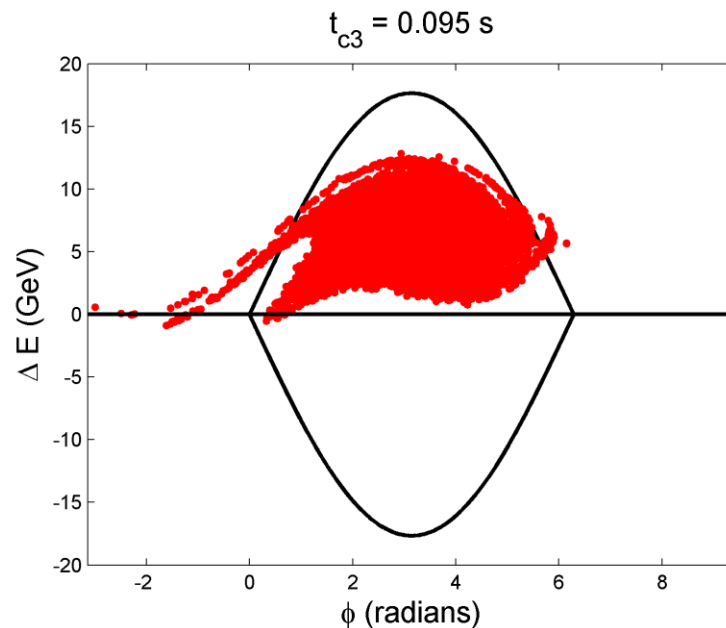
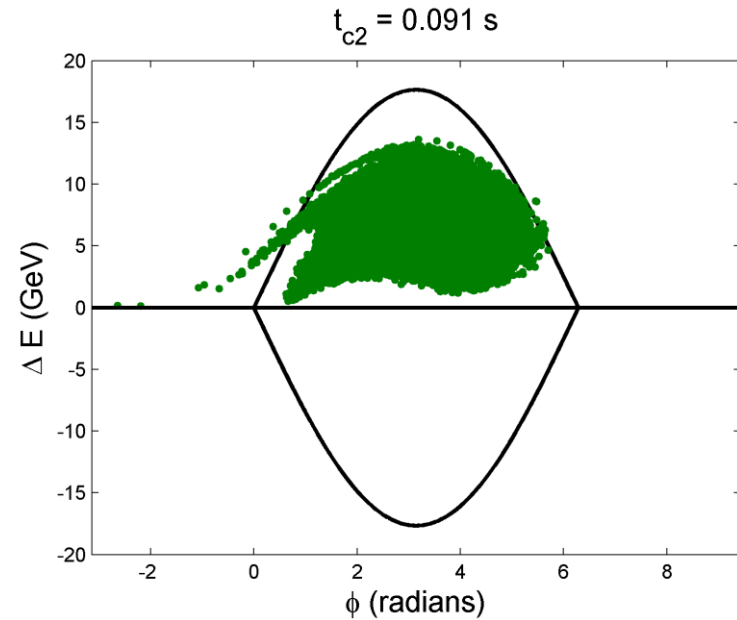
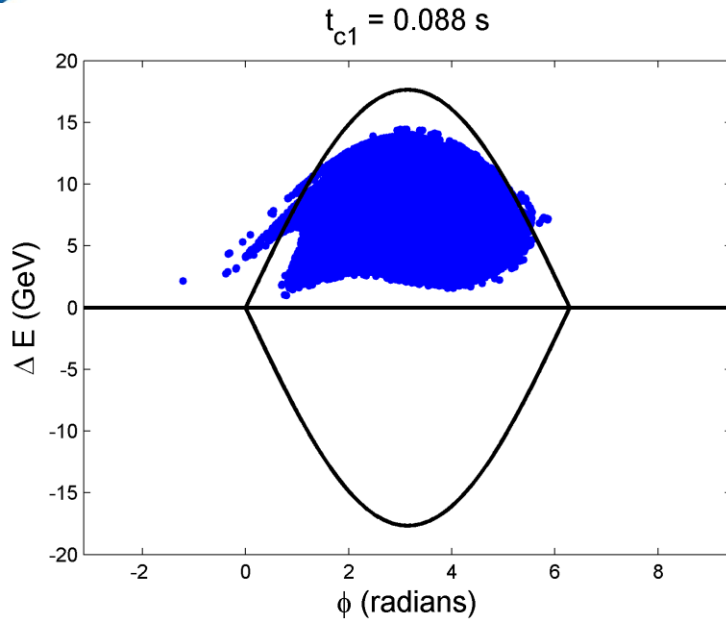
- The RF programs calculated for a single RF for constant filling factor in momentum (0.9)



- Duration of 200 ms:
 - fast compared to the cycle (about 50 s)
 - slow enough to avoid particle losses
- Final energy corresponds to the case of $\alpha = 4$ → bunches are distorted before the end → **optimization of the capture time is needed**



Capture time



□ Recapture bunches when the two RF voltages are in phase → **disturbed shape**

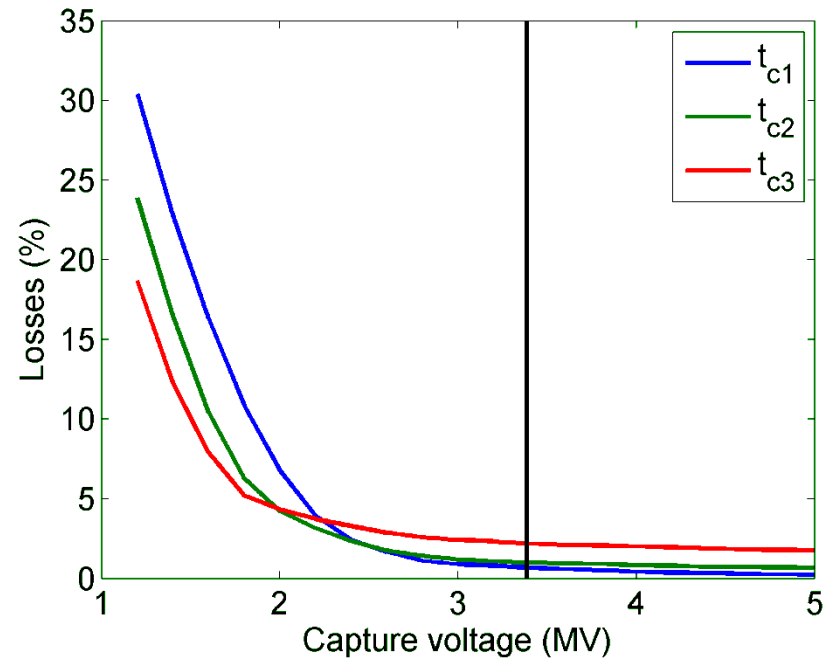
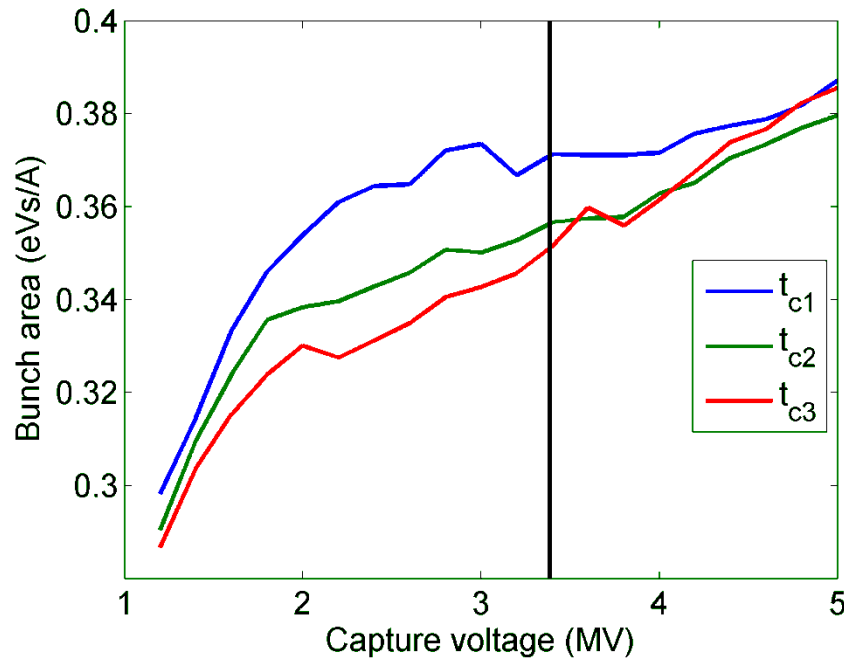
□ While approaching each other in energy more particles are lost.



Beam capture optimization

□ Optimize capture voltage and time with respect to:

- Final emittance
- Particle losses



□ Selection based on minimizing losses → larger longitudinal emittance

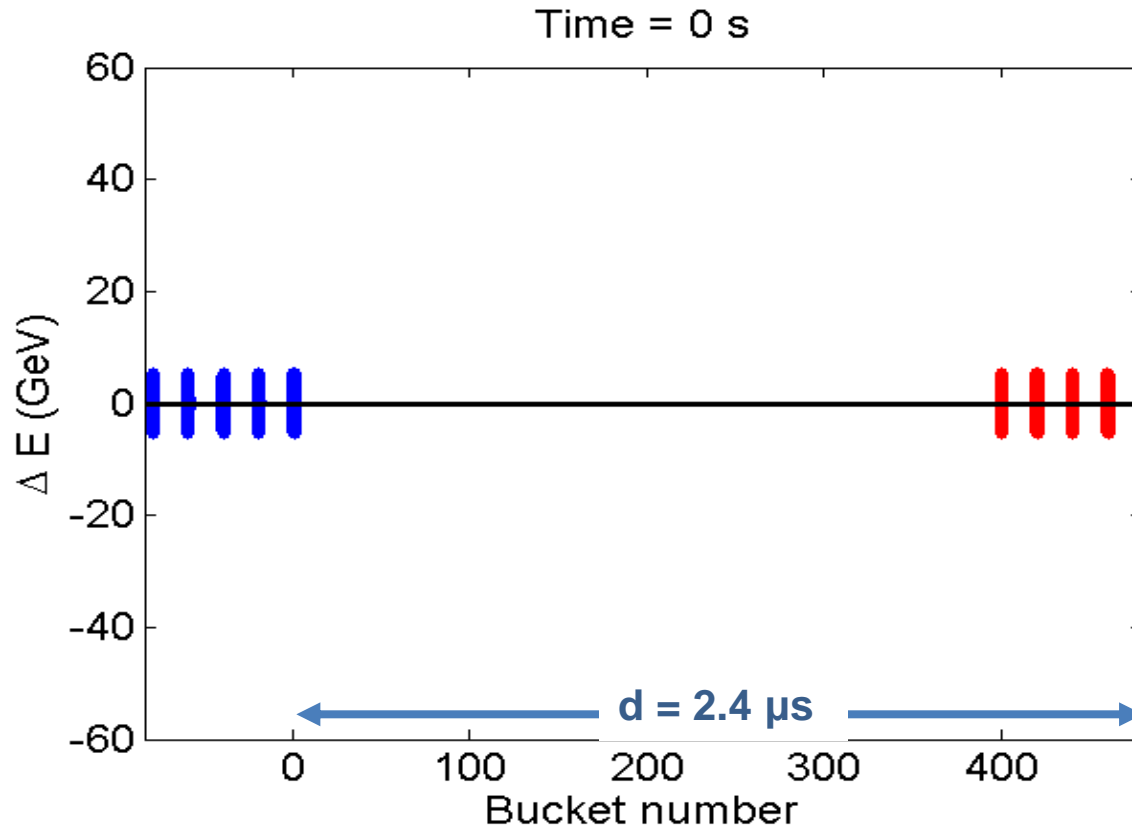
- Capture time: t_{c2}
- Capture voltage: 3.4 MV



- $\epsilon_l \sim 0.35 - 0.36$ eVs/A
- Losses $\sim 1 - 1.5$ %



Example for selected conditions

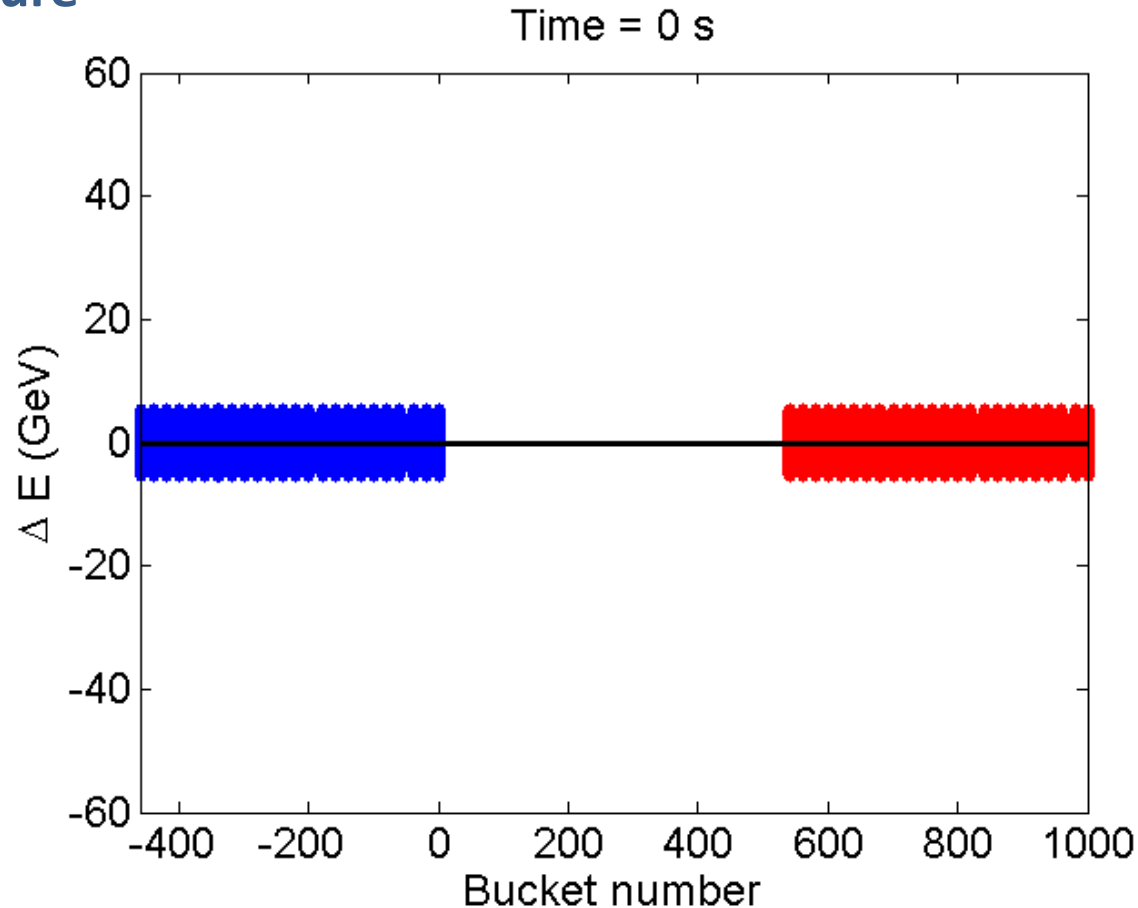


- ❑ Using the designed RF programs (**200 ms**): distance between the last bunch of each batch **$d = 2.4 \mu\text{s}$**
- ❑ Since batch length is **$2.3 \mu\text{s}$** → **very small batch spacing ($T_B = 100 \text{ ns}$)**
- ❑ In reality T_B is **defined by the LLRF specifications**: large enough to assure that each batch is exposed only to the RF voltage of its corresponding pair of 200 MHz TWC (**$T_B > 1.3 \mu\text{s}$**)
- ❑ Extra slipping time at maximum energy separation.



Example with $T_B = 2.7 \mu\text{s}$

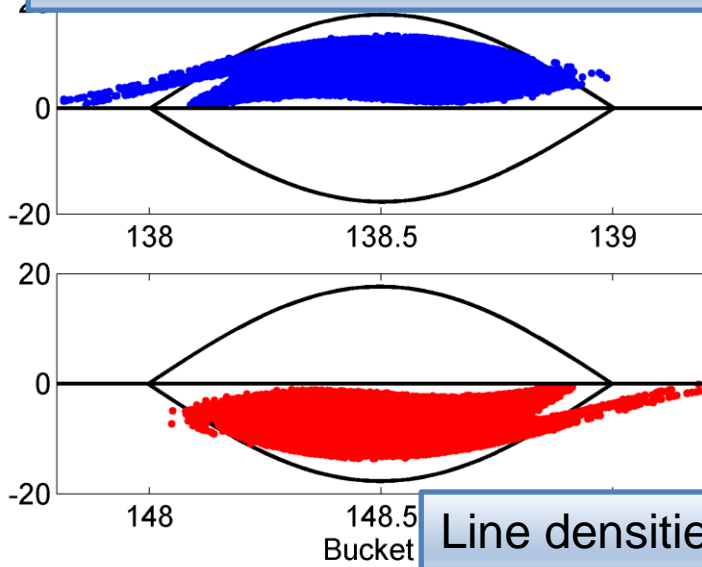
- $T_B = 2.7 \mu\text{s}$ large enough for RF voltage modulation \rightarrow each batch sees only the voltage of one pair of TWC during most part of the procedure



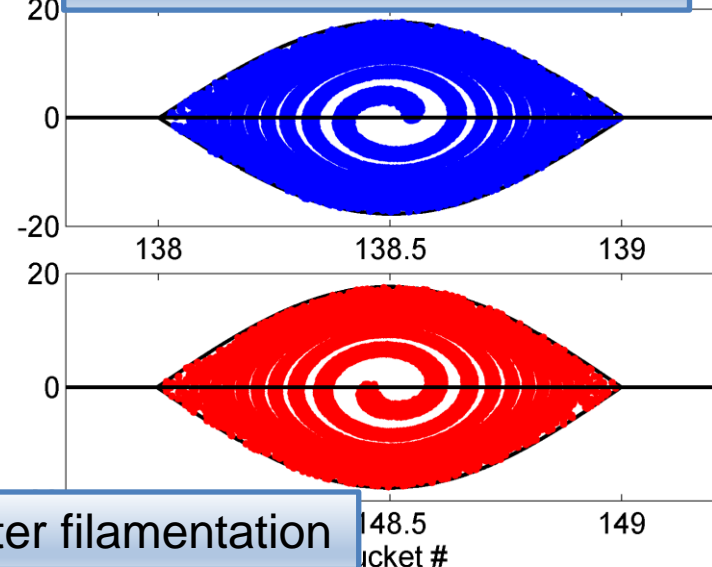
Total duration of around 300 ms

Beam parameters

Bunches just before recapture



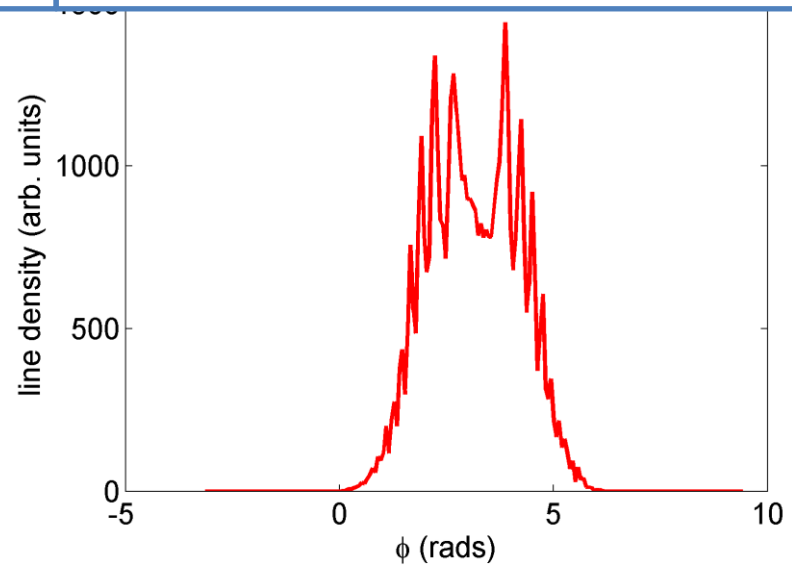
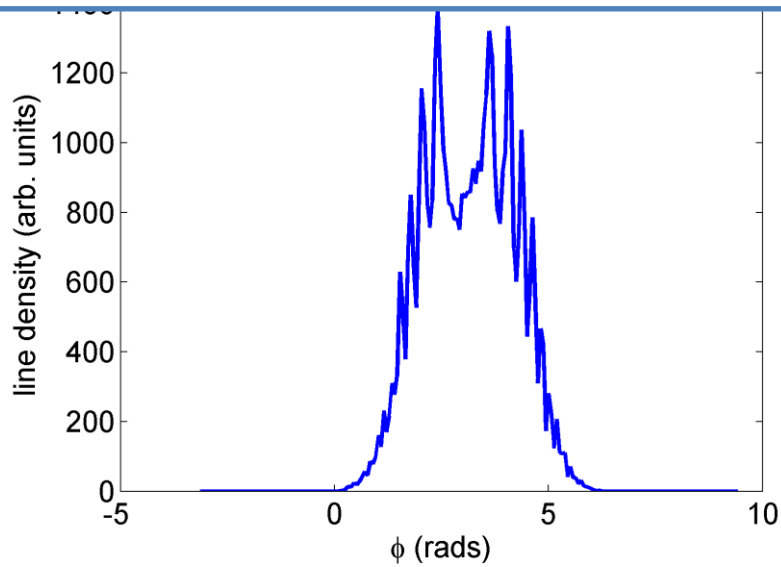
Bunches after filamentation



Line densities after filamentation

$\tau = 3.3 \text{ ns} - \varepsilon = 0.36 \text{ eVs} - \text{losses} = 1.1\%$

$\tau = 3.3 \text{ ns} - \varepsilon = 0.36 \text{ eVs} - \text{losses} = 1.0\%$

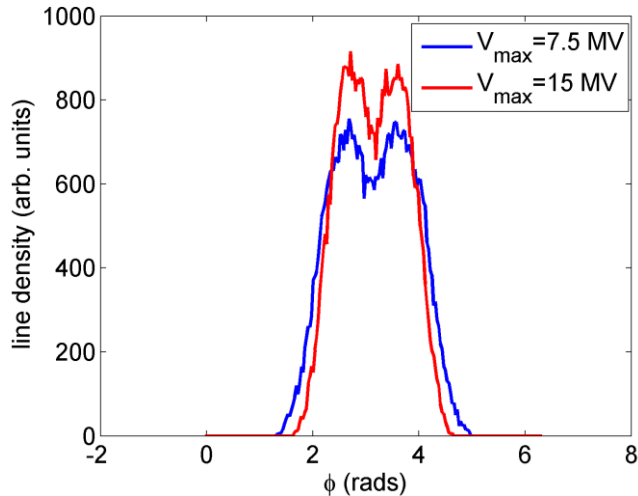




Beam parameters at flat top

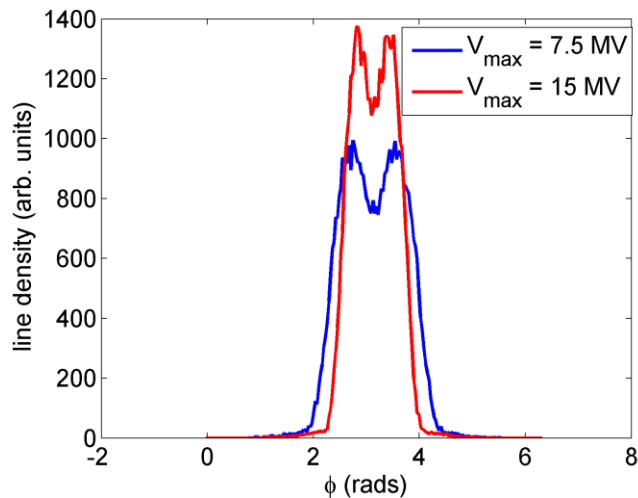
- ❑ Accelerate the beam to top energy
- ❑ Two possible schemes to provide the final bunch length at extraction

I. Adiabatic voltage increase



- $V_{RF} = 7.5$ MV: $\tau = 2.3$ ns
- $V_{RF} = 15$ MV: $\tau = 1.9$ ns
- Total losses = 1.2 %

II. Bunch rotation



- $V_{RF} = 7.5$ MV: $\tau = 1.8$ ns
- $V_{RF} = 15$ MV: $\tau = 1.3$ ns
- Total losses = 1.2 %



Implementation and tests

- ❑ **AM and FM of the RF cavities is foreseen after LS2** (LIU TDR SPS LLRF, P. Baudrenghien, T. Bohl, G. Haggmann): individual beam and cavity controllers

- ❑ Tests can be done before only with one batch (flat top, flat bottom) to:
 - Investigate the beam life time without the phase loop (PL) → unpredicted behavior of the PL during the slip stacking procedure → might be necessary to operate without PL

 - Define the aperture limitation ΔR

 - Test and optimize the designed RF programs regarding the particle losses and the final longitudinal emittance

 - ...



Summary

- ❑ Momentum slip-stacking in the SPS proposed as a potential way of increasing the number of bunches for the nominal I-LHC beams
- ❑ Particle simulations performed to confirm this possibility regarding the beam dynamics (no intensity effects had been included)
- ❑ Small particle losses ($\sim 1-2\%$) when recapture RF voltage is high \rightarrow large emittance blow-up (factor of 3) \rightarrow large bunch length
- ❑ Can be reduced by the **increase of the available RF voltage** (LS2) and by **bunch rotation** before extraction \rightarrow **Acceptable beam parameters for the LHC**
- ❑ Implementation is foreseen after LS2
- ❑ Useful tests can still be performed using only one RF system.



Summary table

- ❑ Simulations performed also with the Q26 optics
 - More sensitive to IBS and space charge effects
 - More promising due to the larger relative bucket area for the same available RF voltage → provides more margin if needed

Summary results of the slip-stacking simulations and beam parameters at extraction.

SP optics	Capture Voltage (MV)	Final emittance (eVs/A)	Losses (%)	Bunch Length at flat top (ns)			
				Bunch compr.		Bunch rot.	
				$V_{RF} = 7.5$ MV	$V_{RF} = 15$ MV	$V_{RF} = 7.5$ MV	$V_{RF} = 15$ MV
Q20	3.4	0.35 – 0.36	1 – 2	2.3	1.9	1.8	1.31
Q26	2.0	0.35 – 0.36	1 – 2	2.0	1.7	1.41	1.05



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